

VERIFICATION OF A TRANSLATION

I, the below named Translator, hereby declare that;

I am the translator of the Japanese specification of  
U.S. Patent Application under Title of the Invention  
" ELECTRON BEAM APPARATUS AND METHOD OF MANUFACTURING  
SEMICONDUCTOR DEVICE USING THE APPARATUS " filed on the 2nd  
day of November, 2001.

That I believe the attached English translation is a  
true and complete translation of said application as filed.

I hereby declare that all statements made herein of my  
own knowledge are true and that all statements made on  
information and belief are believed to be true; and further  
that these statements were made with the knowledge that  
willful false statements and the like so made are punishable  
by fine or imprisonment, or both, under Section 1001 of Title  
18 of the United States Code and that such willful false  
statements may jeopardize the validity of the application or  
any patent issued thereon.

Dated this 27th day of February, 2002

Full name of the Declarant: Sumie OHTSUKA

Signature of the Declarant:

A handwritten signature in cursive script, appearing to read 'S. Ohtsuka', written over a horizontal line.

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